Special Issue

Advancements in Optical Measurement Devices and Technologies

Message from the Guest Editors

We propose a Special Issue on "Advancements in Optical Measurement Devices and Technologies" for the *Metrology* journal. Optical measurement technologies have become critical in various scientific and industrial applications due to their high precision, non-invasive nature, and versatility. This Special Issue aims to gather cutting-edge research and developments in this dynamic field, topics of interest include, but are not limited to, the following:

- **Novel Optical Sensors and Devices:** Innovations in sensor design for enhanced sensitivity, selectivity, and stability.
- **Fiber Optic Sensing Technologies:** Advances in fiber optic sensors for environmental, biomedical, and industrial applications.
- **Laser-Based Measurement Techniques:** Developments in laser interferometry, laser Doppler velocimetry, and laser-induced fluorescence.
- **Imaging and Spectroscopy:** Progress in optical imaging systems, spectroscopy methods, and their integration into measurement technologies.
- **Applications in Metrology:** Case studies and reviews on the application of optical measurement technologies in metrology, including calibration, standardization, and quality control.

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About the Journal

Message from the Editor-in-Chief

Metrology draws together researchers from diverse areas of metrology or measurement technology in a wide variety of applications. I encourage you to submit your manuscripts for consideration or publication in the area of measurement engineering, according to the scope of the journal. *Metrology* is supported by our authors and their institutes through low article processing charges (APC) for accepted papers. We hope you will support the journal by becoming one of our authors.

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